



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **IBARA, Yoshikazu et al.**

Group Art Unit: 2823

Serial No.: 09/892,893

Examiner: **COLEMAN, William D.**

Filed: **June 28, 2001**

P.T.O. Confirmation No.: 1585

For: **METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICES**

**AMENDMENT UNDER 37 CFR § 1.111**

Commissioner for Patents  
Washington, D.C. 20231

December 2, 2002

Sir:

In response to the Office Action dated August 1, 2002, the period for response therefor extended by a Petition for a One-Month Extension of Time, please amend the above-identified application as follows:

**IN THE TITLE:**

Amend the title as follows:

**METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICES WITH SILICIDE  
FILMS THEREON**

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47/A  
12/21/02  
jwm.